

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Miller et al.**

Serial No.: 09/863,979

Filed: May 23, 2001

For: **Method and Apparatus for  
Deposition of Porous Silica Dielectrics**§  
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Group Art Unit: 1763

Examiner: **Lund, Jeffrie Robert**

Attorney Docket No.: 98-197/1D

FAX RECEIVED

JUN 11 2003  
GROUP 1700# 16001E  
6/12/03  
mwCertificate of Transmission Under 37 C.F.R. § 1.8(a)I hereby certify this correspondence is being transmitted via  
facsimile to the Commissioner for Patents, P.O. Box 1450,  
Alexandria, VA 22313-1450, facsimile number (703) 872-  
9311, on June 10<sup>th</sup>, 2003.

By: \_\_\_\_\_

Amelia C. Neering  
Amelia C. NeeringRESPONSE TO FINAL OFFICE ACTIONCommissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

No fees are believed to be required. If, however, any fees are required, I authorize the Commissioner to charge these fees which may be required to LSI Logic Corporation Deposit Account No. 12-2252. No extension of time is believed to be necessary. If, however, an extension of time is required, the extension is requested, and I authorize the Commissioner to charge any fees for this extension to LSI Logic Corporation Deposit Account No. 12-2252.

In response to the Final Office Action dated March 13, 2003, please amend the above-identified application as follows: